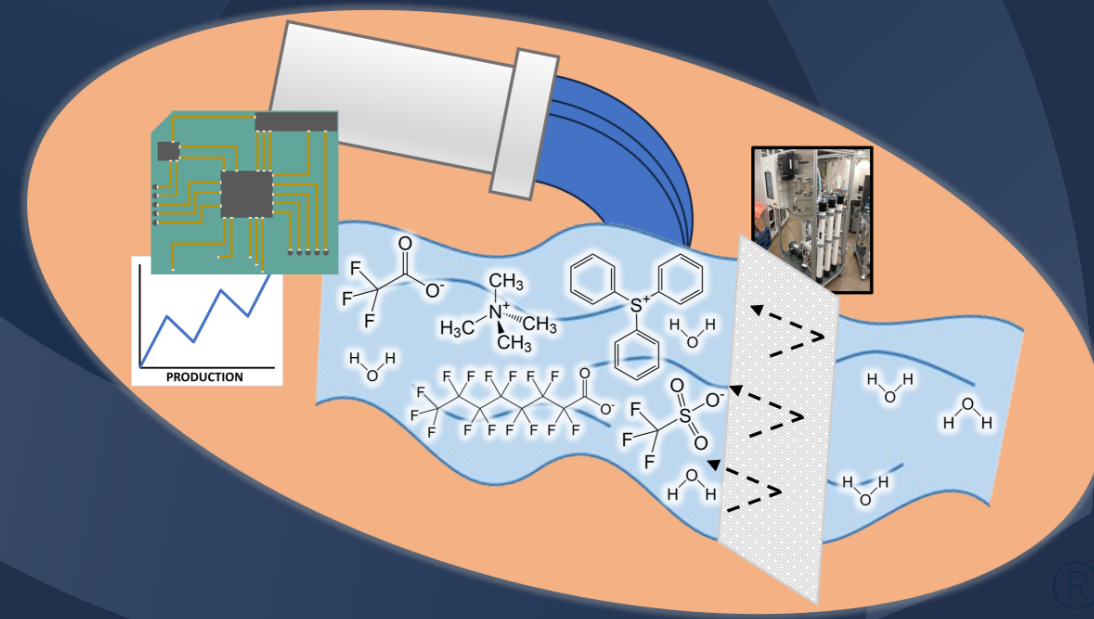


Use of High-Pressure Membranes for the Industrial Pretreatment of PFAS in Semiconductor Wastewater

6/6/24

Aron Griffin, Chris Bellona, Timm Strathmann

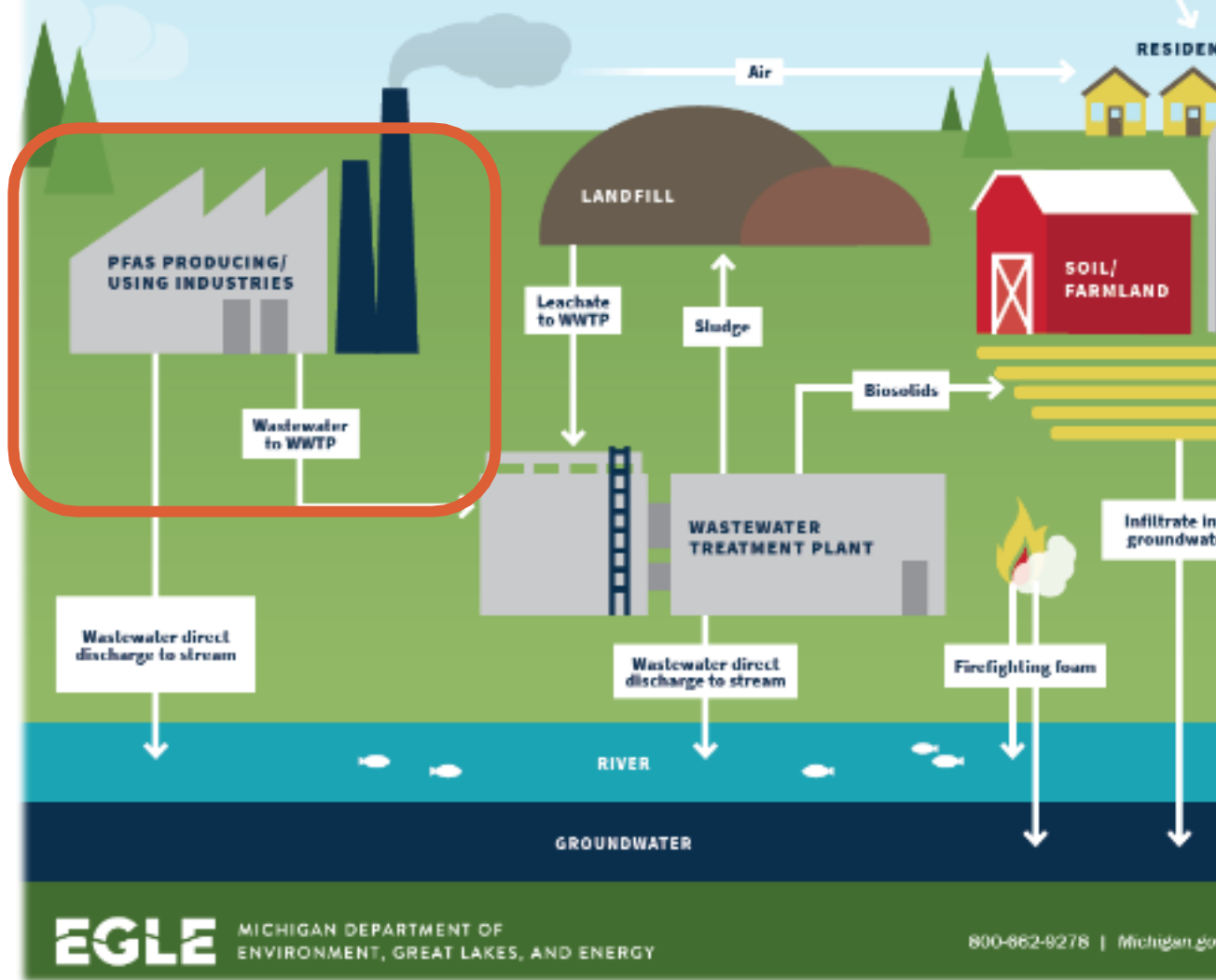
Civil and Environmental Engineering



Outline

1. Semiconductor Manufacturing (FAB) Background
2. Membrane treatment of FAB Wastewater
3. Ultrashort PFAS Rejection Evaluation

PFAS Cycle



Study of PFAS Influent to POTWs

The EPA will collect nationwide data on industrial discharges of per- and polyfluoralkyl substances (PFAS) to publicly owned treatment works (POTWs). The **POTW Influent PFAS Study** will include analysis of indirect discharges from categories recently reviewed by the agency and categories identified as discharging PFAS, but for which insufficient monitoring data exist.

On this page:

- [Background](#)
- [Study Design](#)
- [Draft Questionnaire](#)
- [Additional Information](#)



Micron Pledges Up to \$100 Billion for Semiconductor Factory in New York

The company is planning a giant complex in Clay, N.Y., a sign that the government's investments in semiconductors are steering firms' decisions.

What does Micron's estimated 48 million gallons of water per day mean?

WRVO | By Ava Pukatch
Published August 17, 2023 at 5:17 AM EDT

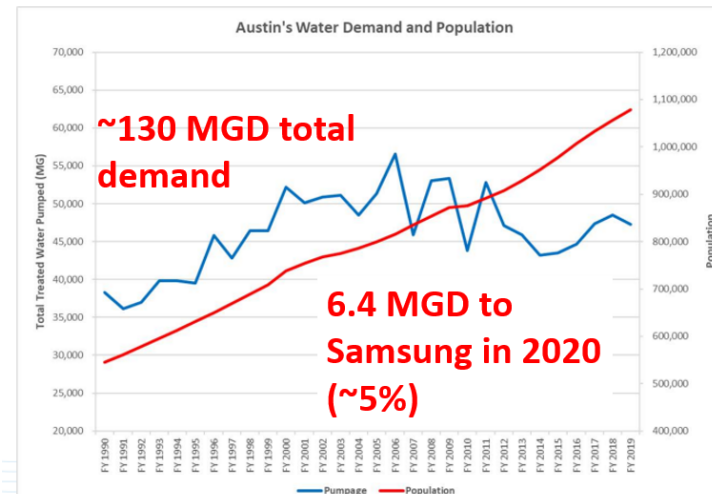
FABs require significant water resources



Administration Priorities The Record

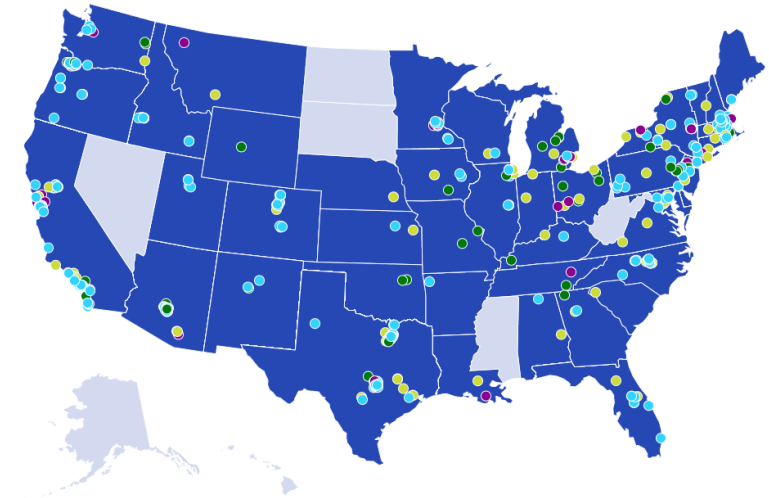
APRIL 25, 2024

FACT SHEET: President Biden Announces up to \$6.1 Billion Preliminary Agreement with Micron under the CHIPS and Science Act

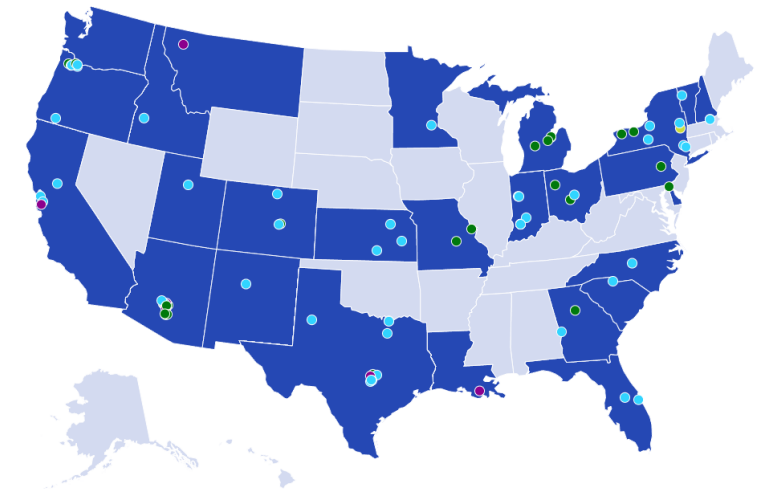


Current facilities

● Semiconductors ● Equipment ● Materials ● University R&D Partner



New or expanded

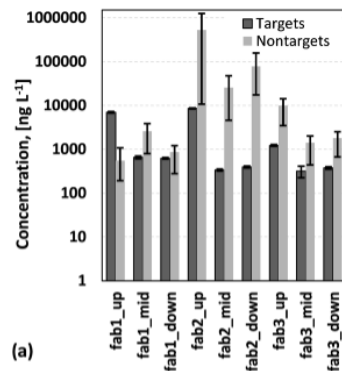


Target and Nontarget Analysis of Per- and Polyfluoroalkyl Substances in Wastewater from Electronics Fabrication Facilities

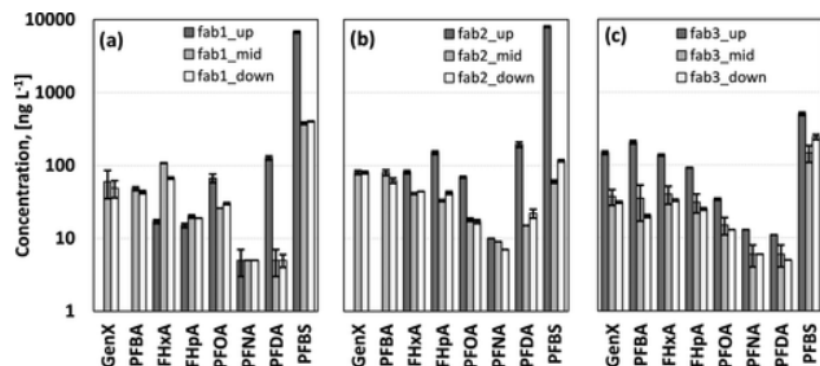
Paige Jacob, Krista A. Barzen-Hanson, and Damian E. Helbling*

Cite This Environ. Sci. Technol. 2021, 55, 2346–2356

Read Online



(a)



Rapid and Simultaneous Quantification of Short- and Ultrashort-Chain Perfluoroalkyl Substances in Water and Wastewater

Paige Jacob and Damian E. Helbling*

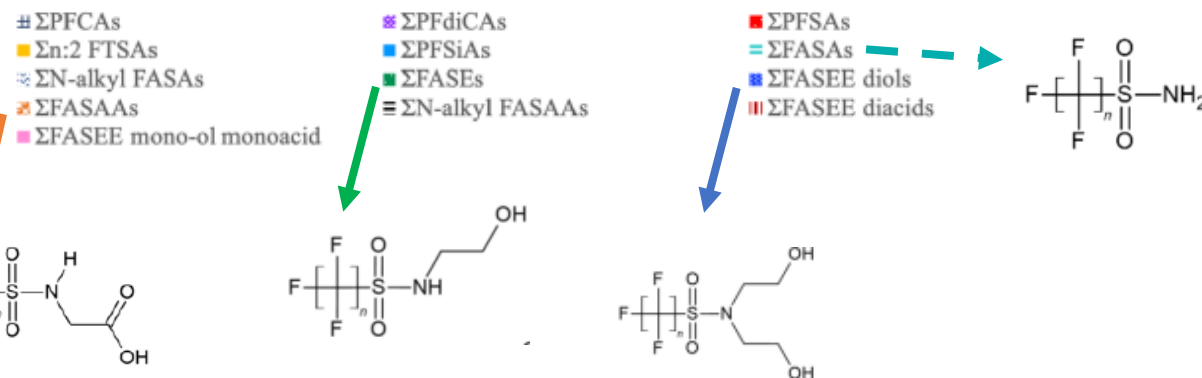
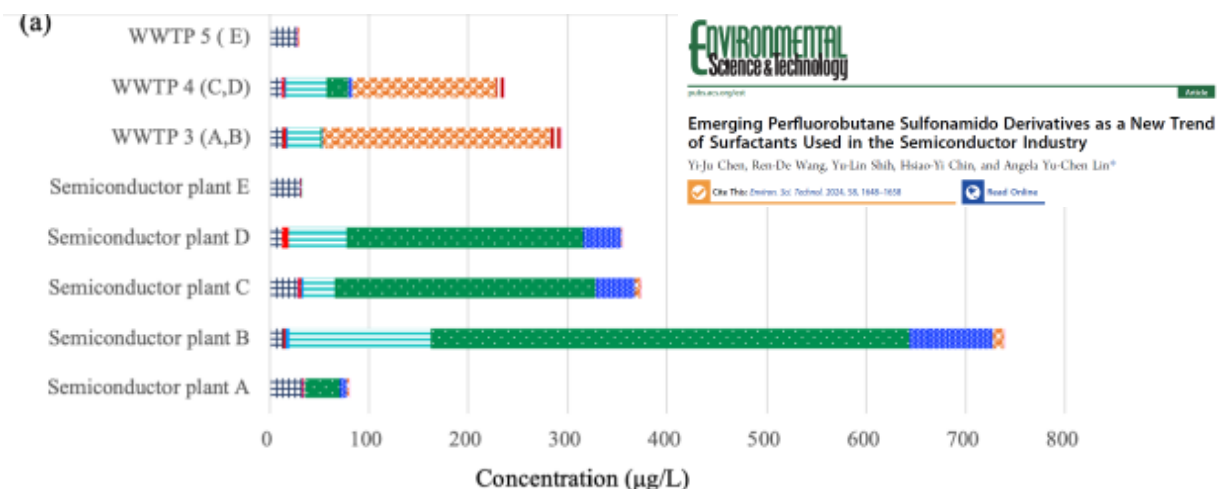
Cite This ACS EST Water 2021, 1, 118–128

Read Online

Table 3. Average and Standard Deviations of PFAS Concentrations (ng L⁻¹) in Industrial and Commercial Water Samples

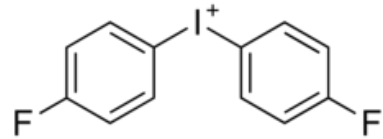
	TFA	PFPrA	PFBA	PFPeA	PFHxA	TFMS	PFEtS ^c	PFPrS	PFBS	PFPeS	PFHxS
Fab 1 WW	4133 ± 166	1125 ± 138	937 ± 58	124 ± 0	145 ± 4	173 ± 101	33 ± 2	ND	70 ± 15	ND	ND
Fab 2 WW	1571 ± 40	237 ± 34	214 ± 8	35 ± 1	46 ± 3	175 ± 9	0.4 ± 0.1	9 ± 0	108 ± 5	ND	ND
Fab 3 WW	15280 ± 78	4184 ± 183	2645 ± 261	394 ± 24	348 ± 25	121 ± 15	4 ± 1	ND	160 ± 9	ND	<LOQ

FAB wastewater contains a variety of PFAS

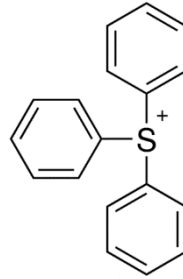


More than just PFAS is present!

Photoacid generating compounds (PAGs)

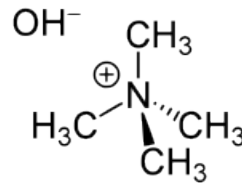


*Diaryliodonium
(DIA)*



*Triphenylsulfonium
(TPS)*

Organic Bases



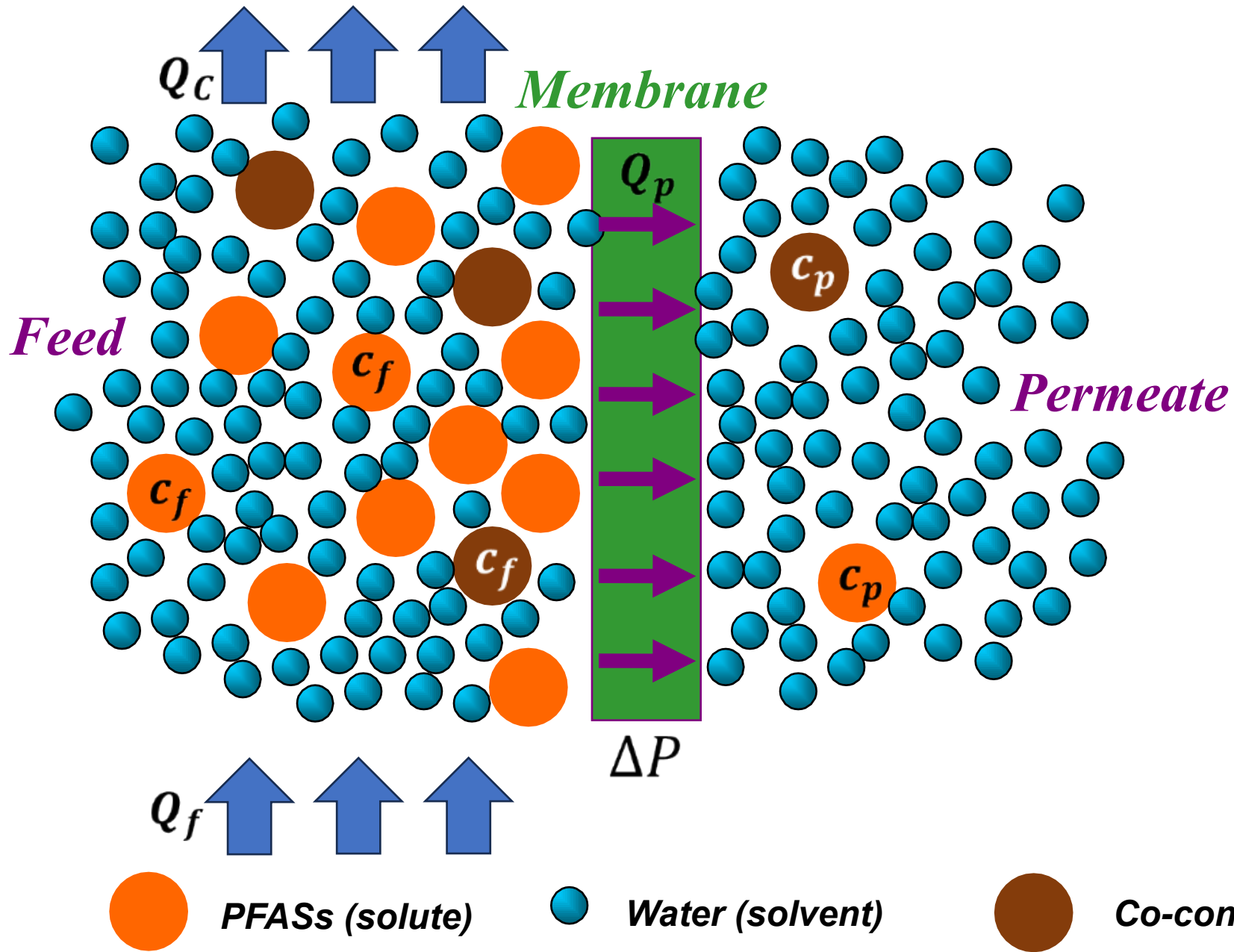
*Tetramethylammonium hydroxide
(TMAH)*

Also...

- High MW polymers
- Hydrogen peroxide
- Ammonium
- Metal nanoparticles
- Surface active organics
- Elevated TOC

Complicates treatment!!

1. **Semiconductor Manufacturing (FAB) Wastewater**
FAB wastewater contains varied PFAS in a complex matrix
2. **Membrane treatment of FAB Wastewater**



Performance metrics

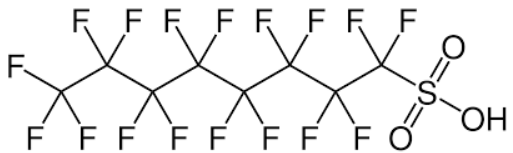
$$Rejection = \left(1 - \frac{c_p}{c_f} \right) * 100$$

$$Recovery = \frac{Q_p}{Q_f} * 100$$

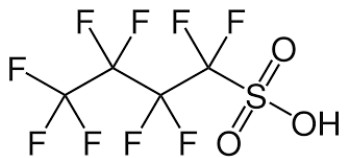
Rejection Mechanisms

Steric

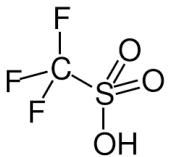
$R_s \approx MW$
(g/mol)



499

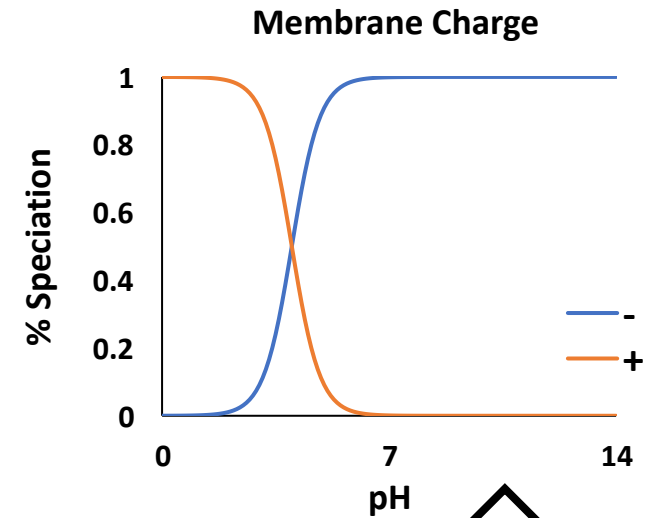
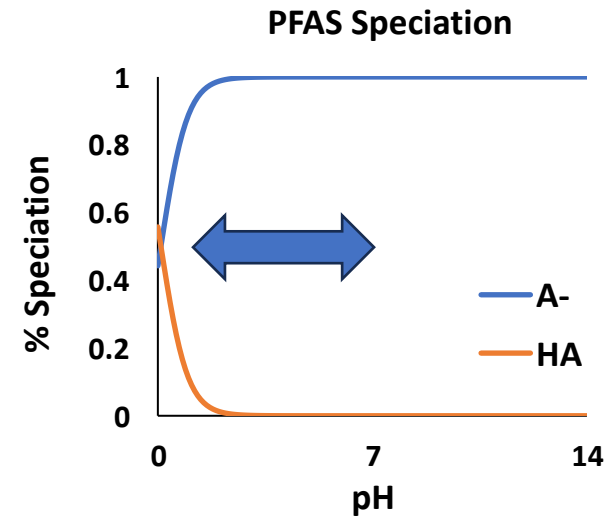


299

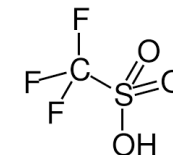
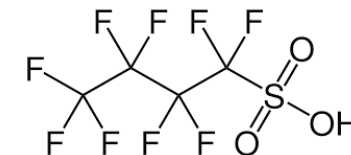
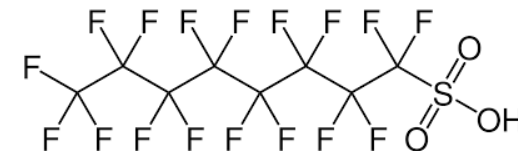


149

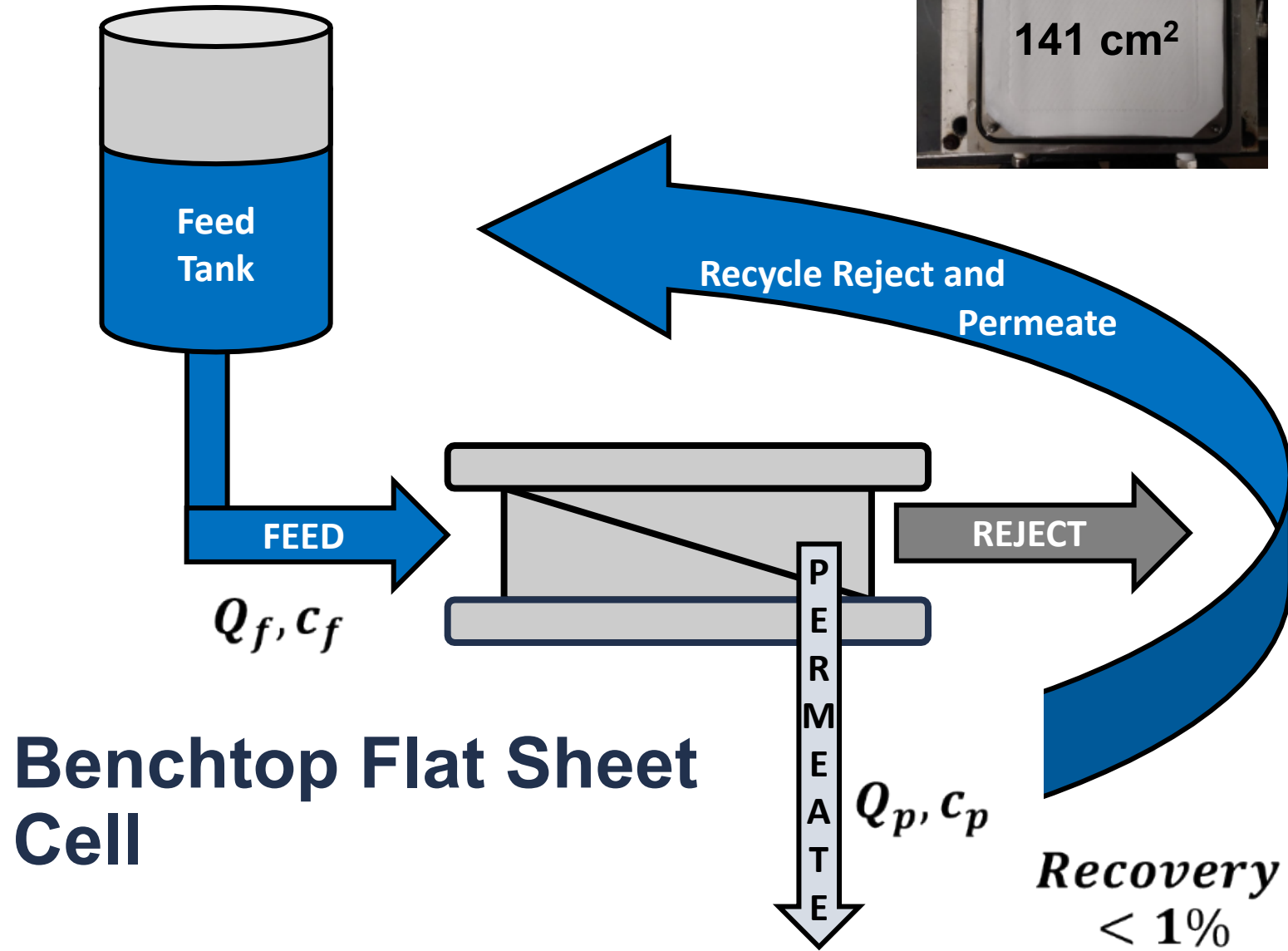
Electrostatic



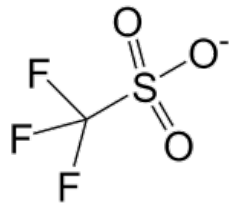
Compound-Membrane



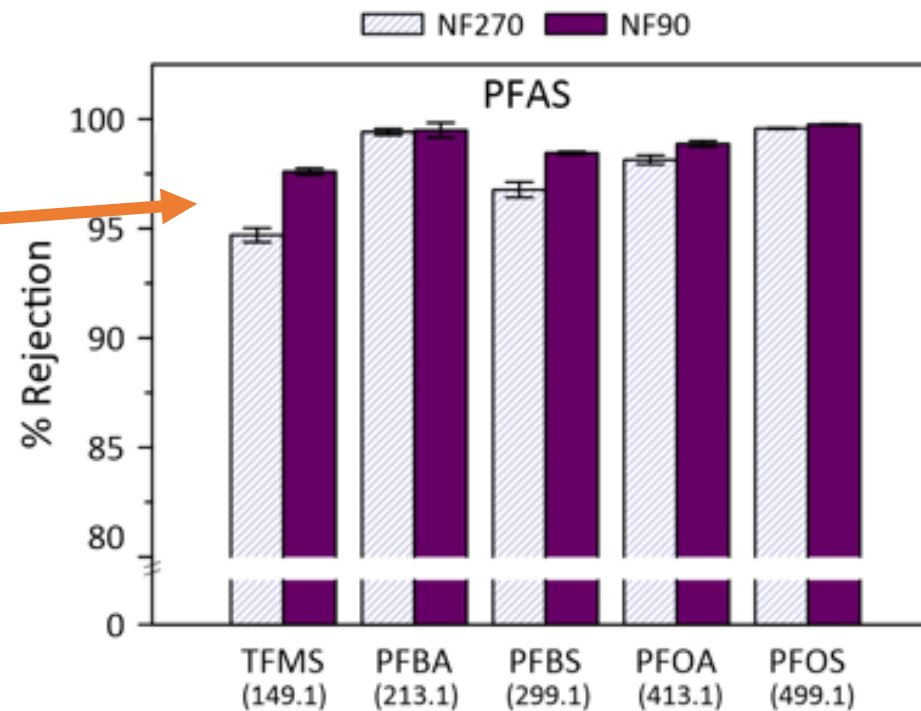
PARTITIONING



“Tight” NF membrane performed well for all PFAS compounds evaluated on bench system



Ultrashort trifluoromethane sulfonic acid (TFMS)

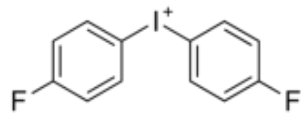


- Increasing rejection with chain length
- Anionic compounds → repulsion

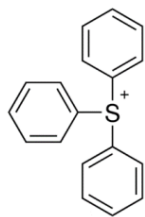
Electrostatic and compound-membrane interactions important for organic co-contaminant rejection

Fab Contaminants (cations)

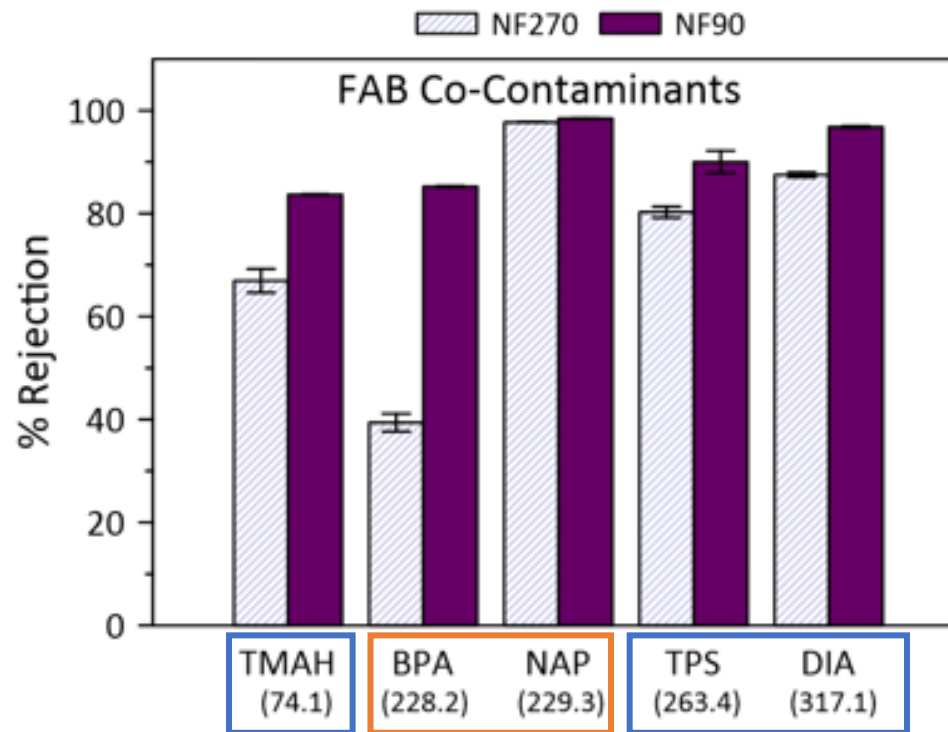
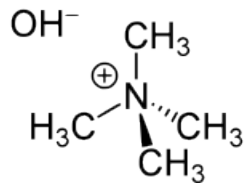
DIA



TPS

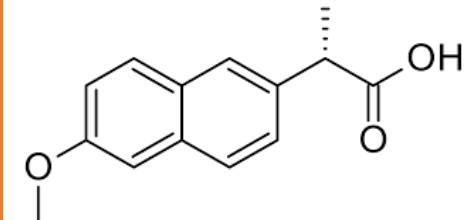


TMAH

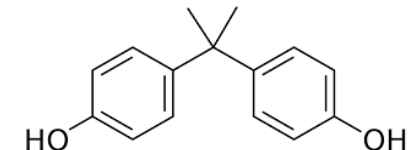


Charge Investigation (surrogates)

Naproxen (NAP)
Anion

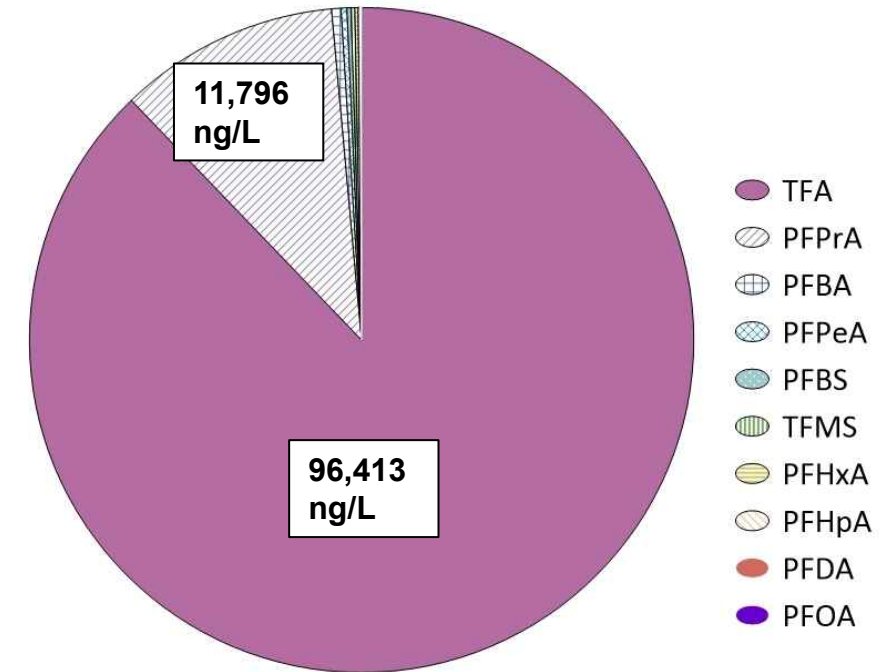


Bisphenol-A (BPA)
neutral

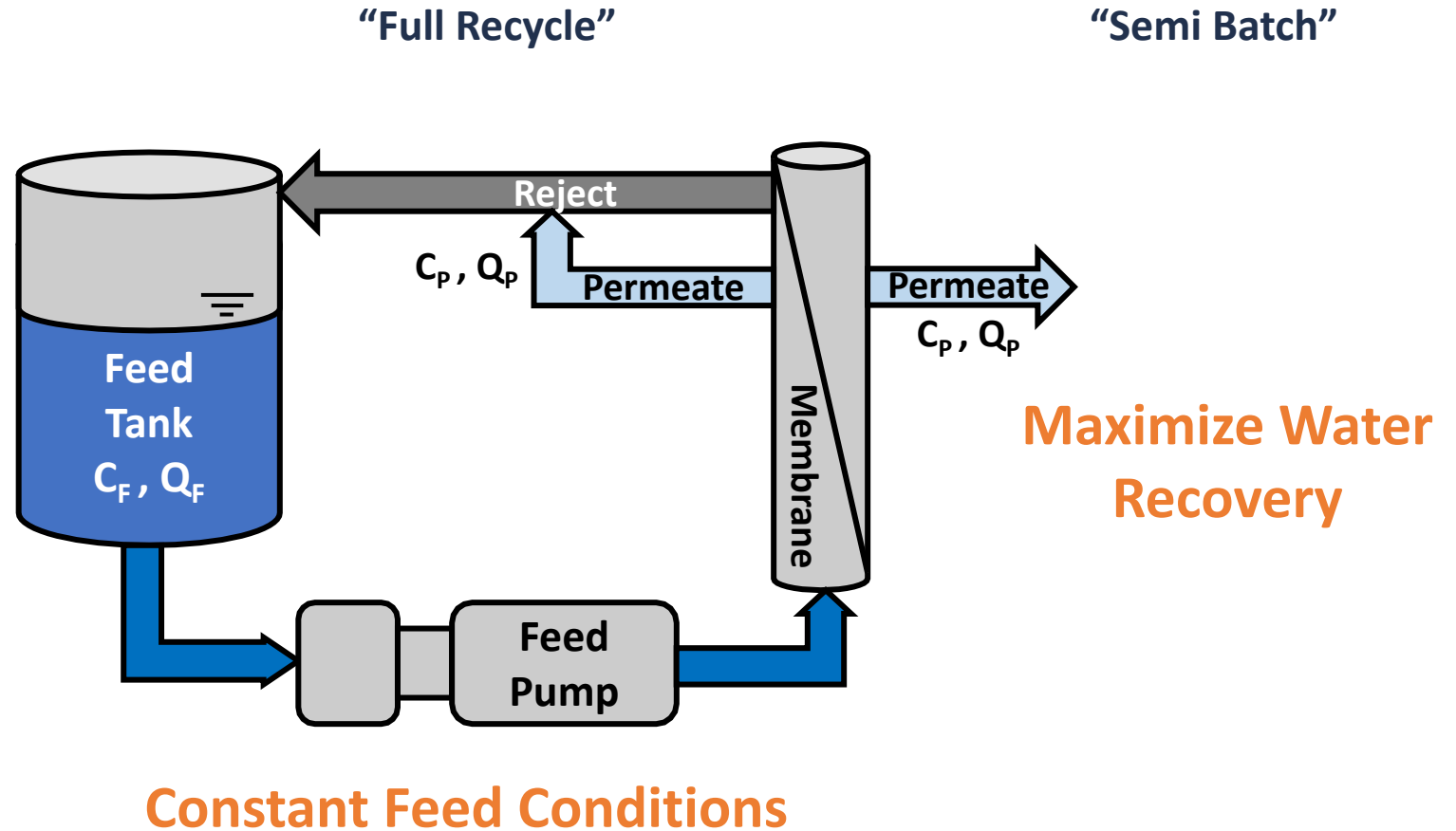


Collected FAB wastewater contained high concentrations of ultrashort PFCAs

Category	Compound	Concentration
PFAS	TFMS	202 ng/L
	TFA	96,413 ng/L
	PFPrA	11,796 ng/L
	PFBA	504 ng/L
	PFBS	213 ng/L
	PFPeA	310 ng/L
	PFHxA	178 ng/L
	PFHpA	85 ng/L
	PFOA	38.0 ng/L
	PFNA	17.2 ng/L
	PFDA	57.3 ng/L
Water Quality	pH	6.9
	Conductivity	2,000 mS/cm
	Fl ⁻	121 mg/L
	Cl ⁻	24.5 mg/L
	NO ₃ ⁻	15.9 mg/L
	PO ₄ ³⁻	19.2 mg/L
	SO ₄ ²⁻	766 mg/L
	TOC	8.7 mg/L
	TN	93.4 mg/L



NF90 pilot system used in batch configuration to achieve 90% recovery

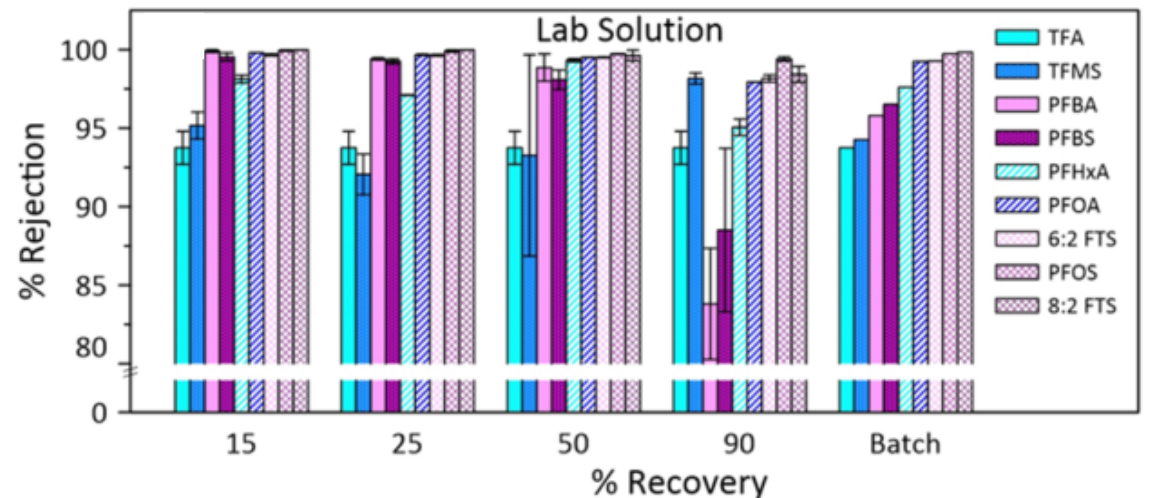
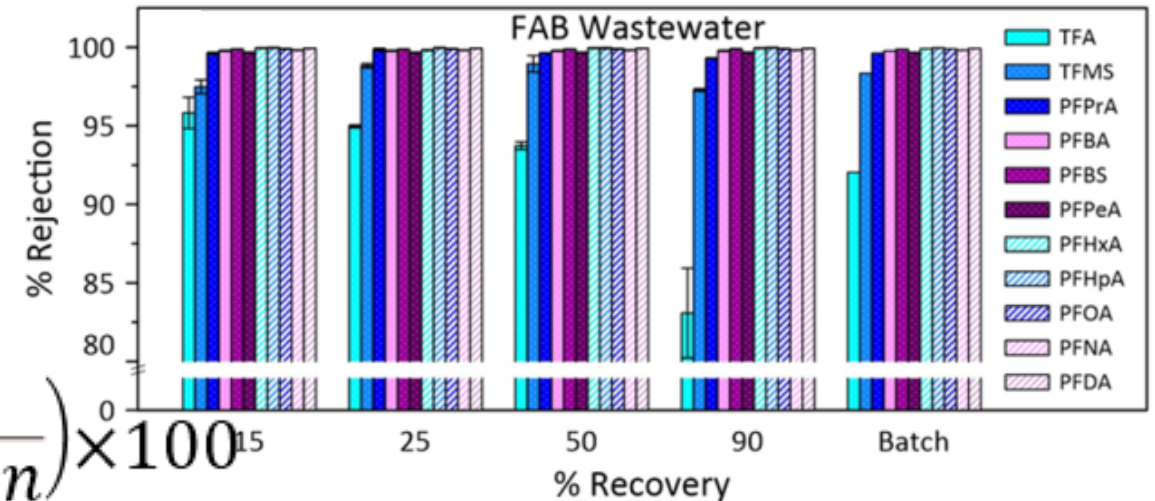


High rejection of PFAS at 90% recovery

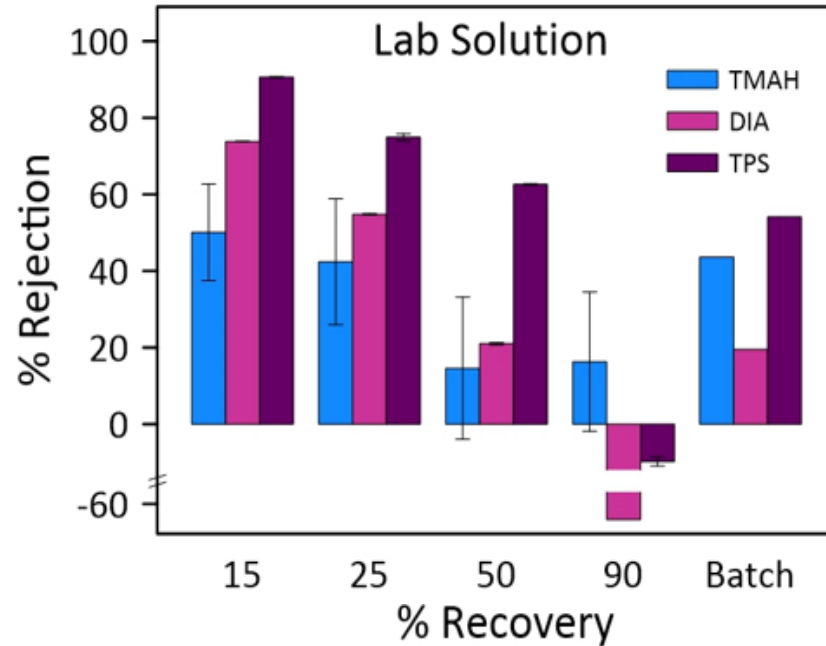
- 92% and 98% batch rejection of ultrashort TFA and TFMS
- >99% rejection of all other compounds

$$Rejection = \left(1 - \frac{\text{permeate concentration}}{\text{original feed concentration}}\right) \times 100$$

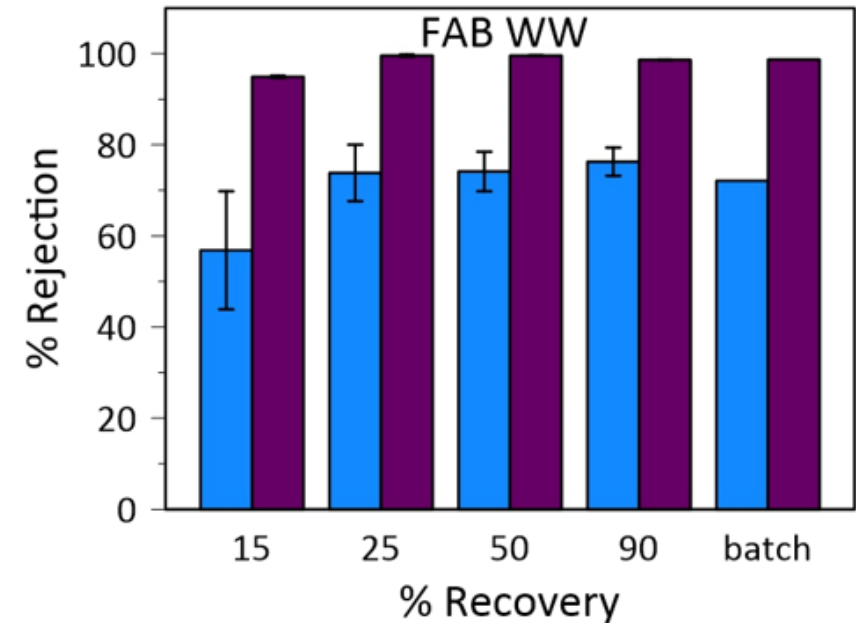
- Lower rejection in spiked DI water
- PFAS coordination with matrix constituents



Improved rejection of co-contaminants also observed



- “Negative” rejection observed in spiked DI water



- Decreased electrostatic attraction and compound-membrane interaction

- 1. Semiconductor Manufacturing (FAB) Wastewater**
FAB wastewater contains varied PFAS in a complex matrix
- 2. Membrane treatment of FAB Wastewater**
Membranes effective for removal of PFAS and co-contaminants
- 3. Ultrashort PFAS Rejection Evaluation**

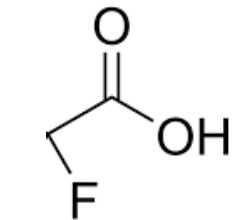
Flat sheet experimental conditions



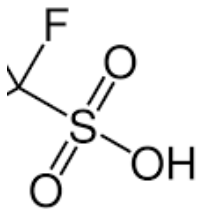
Class	# Carbons	MW g/mol	pKa
Perfluorocarboxylic acids (PFCAs)	2, 3, 4, 8	113 - 413	<2
Perfluorosulfonic acids (PFSAs)	1, 2, 3, 4, 8	149 - 499	<1
Perfluorosulfonamides (FOSAs)	4	298	~6

- As MW ↓, will rejection ↓?

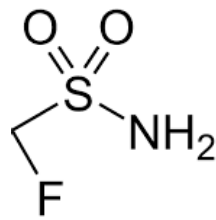
- As pKa ↑, will rejection ↓?



PFCAs



PFSAs



FOSAs

Background Electrolyte	pH	Ionic Strength mM
NaCl	4	1
	7	1 10
NaSO ₄	7	10
CaCl ₂	7	10

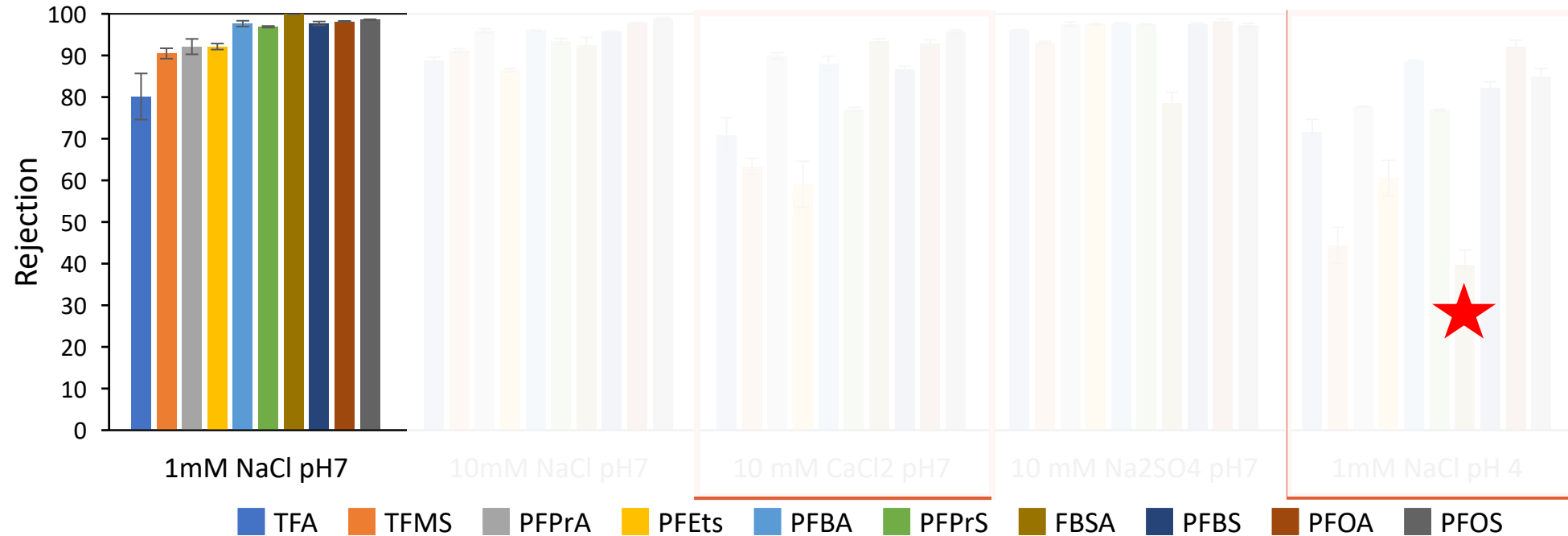
- As pH ↓ will rejection ↓?

- Does ionic composition impact rejection?

Membranes Evaluated	Pore Size nm
NF270	0.36-0.44
NF90	0.29-0.39
BW30	NA?

- Electrostatic vs steric interactions as pore size ↓

NF270 performance variable in different matrices

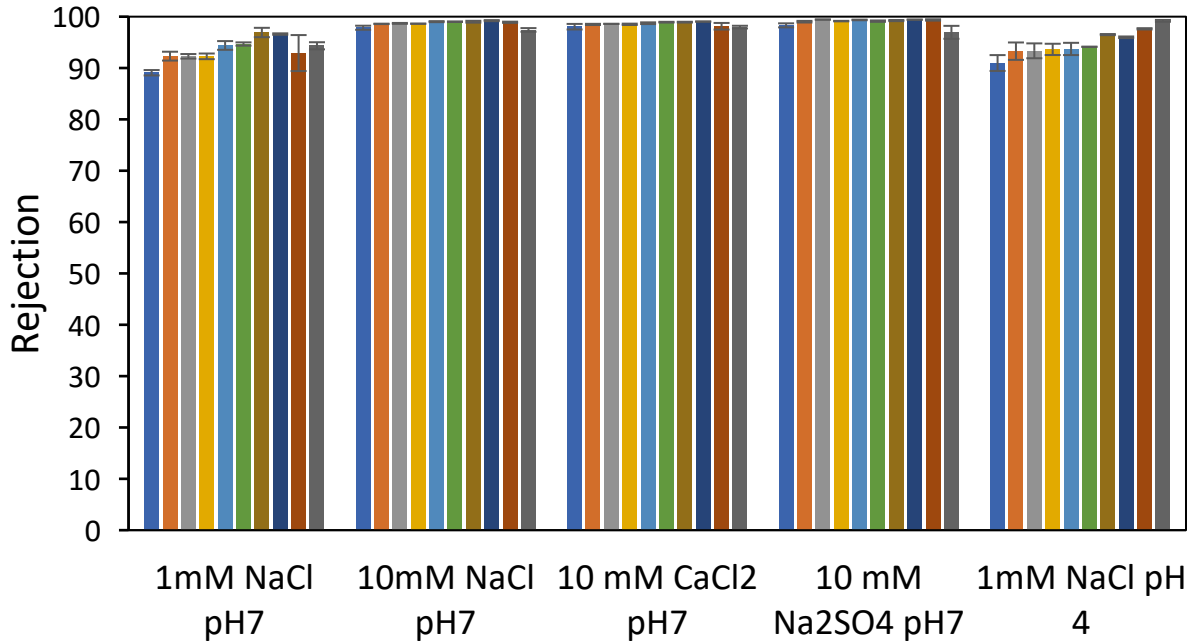


- Ca^{2+} and pH=4 may neutralize or reverse membrane charge and decrease electrostatic repulsion of anionic PFAS
- FBSA rejection impacted at low pH due to protonation of sulfonamide

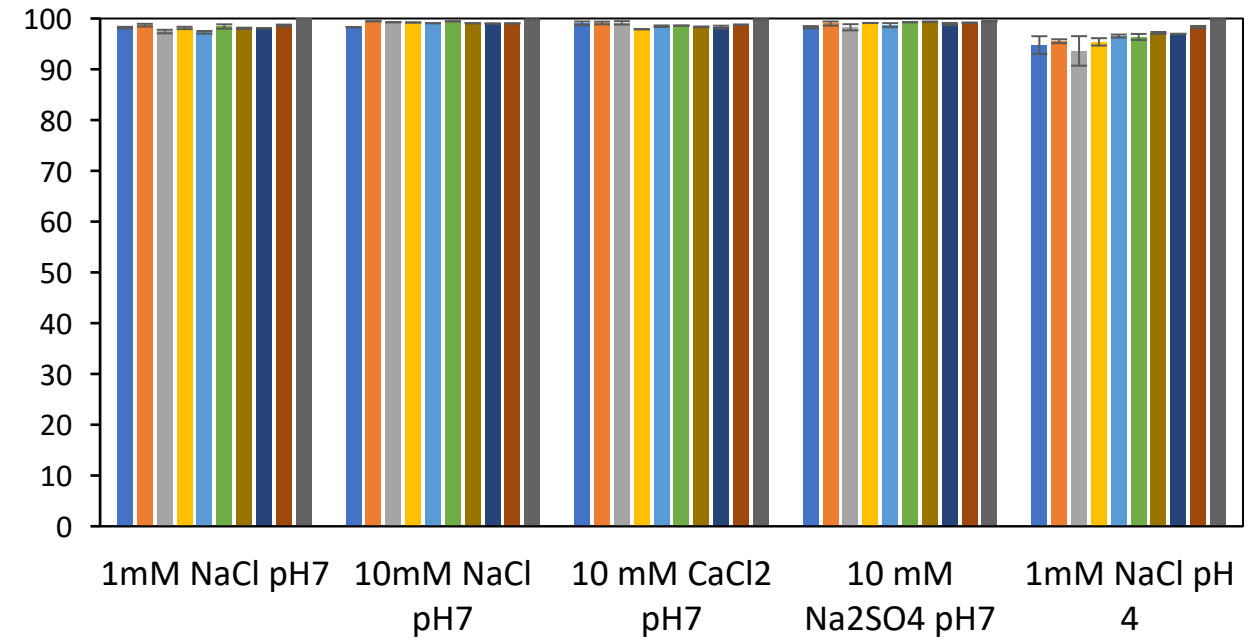
NF90 and BW30 provide more consistent rejection

TFA TFMS PFPrA PFEts PFBA PFPrS FBSA PFBS PFOA PFOS

NF90



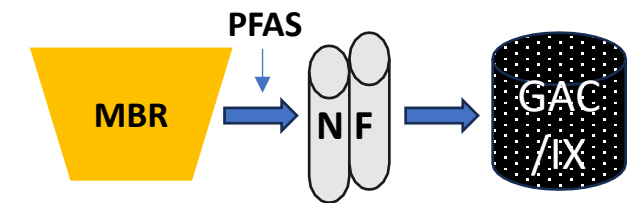
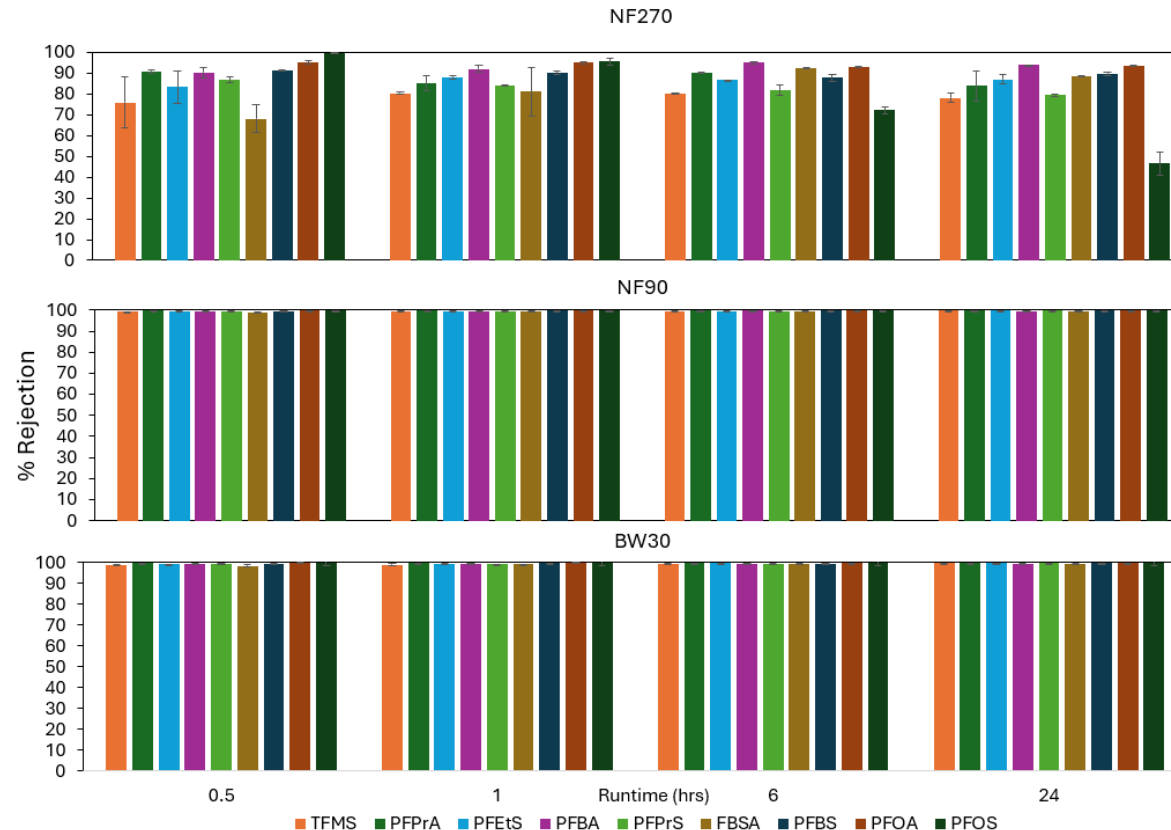
BW30



- Elevated rejection at higher ionic strengths
- Potential evidence of PFOS adsorption

- Chain length dependence only evident at pH 4 where electrostatic repulsion decreased

Similar rejection in spiked campus wastewater



- Prepping for long term demonstration at campus WWTP

Comparing multiple transport models

Pore Flow

$$J_i = -K_{i,d}D_{i,\infty}\frac{dc_i}{dx} + K_{i,a}c_iJ_v + \frac{z_i c_i K_{i,d} D_{i,\infty} F}{RT} \frac{d\Phi(x)}{dx}$$

= *Diffusion + Advection + Electromigration*

- Can account for PFAS charge
- Not suitable for complex matrices
- Using for flat sheet amended DI experiments

Phenomenological

$$J_s = -P \cdot \left(\frac{dc_s}{dx} \right) + J_v(1 - \sigma)c_s$$

= *Diffusion + Advection*

- No electromigration component
- Could also be applied to field studies

Solution Diffusion

$$J_s = \frac{D_s K_s}{l} (c_{i,0} - c_{i,\Delta x})$$

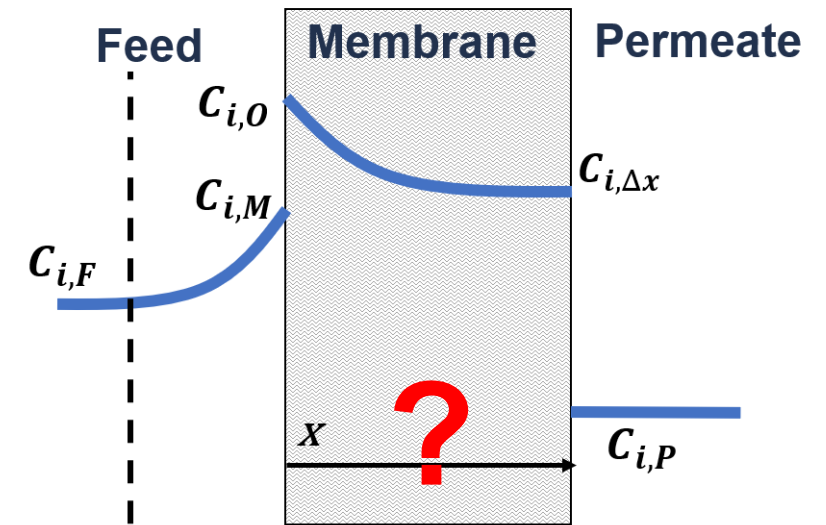
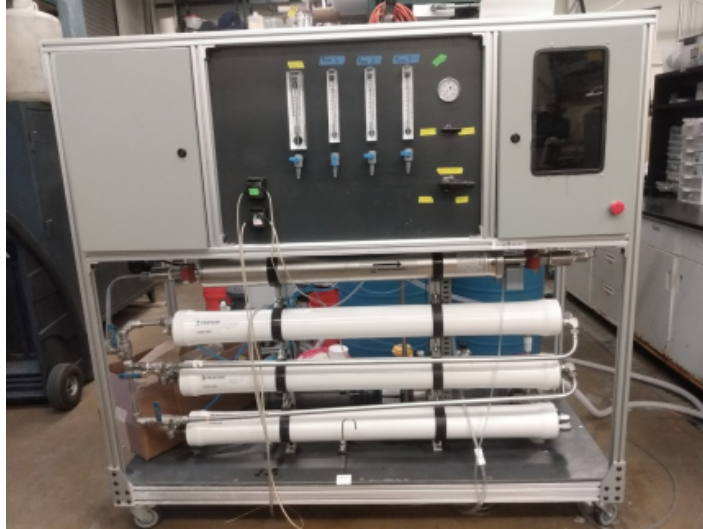
= *Diffusion*

- Past organic micropollutant studies incorporated adsorption terms

Conclusions

- Membranes effective for industrial pre-treatment of FAB wastewater
- Able to remove of long, short, and ultrashort PFAS
- Electrostatic impacts important for loose NF membranes

Next Steps



Thank you!

aronggriffin@mines.edu



Timm Strathmann



Chris Bellona



Task 3037.001